

AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application:

LISTING OF CLAIMS:

1. (currently amended): A method of managing manufacturing processes including at least a batch-process for a batch which comprises plural product lots by at least a batch-manufacturing apparatus, said method comprising the steps of:

transferring a loading request from the batch-manufacturing apparatus to a host computer;

retrieving batch-processable product lots by the host computer to form a batch of plural batch-processable product lots;

carrying the batch to the batch-manufacturing apparatus;

verifying determining by batch-manufacturing apparatus whether ~~or not~~ a [[lot]] number of the lots in the batch reaches has reached a predetermined maximum ~~batch lot number~~;

sending an additional loading request from the batch-manufacturing apparatus to the host computer when the number of lots in the batch has not reached the predetermined maximum;

~~retrieving determining~~ by the host computer whether ~~or not~~ any further additional batch-processable product lot is present; and

carrying the additional batch-processable product lot to the batch-manufacturing apparatus to add the additional batch-processable product lot to the batch when the number of lots has not reached the predetermined maximum and the additional batch-processable product lot is present.

2. (currently amended): The method as claimed in claim 1, wherein the additional loading request is repeatedly sent to the host computer until the [[lot]] number of lots in the batch reaches the predetermined maximum ~~batch lot number~~.

3. (currently amended): The method as claimed in claim 1, wherein a delete request for deleting the additional loading request is sent from the batch-manufacturing apparatus to the host computer either when the [[lot]] number of the lots in the batch reaches the predetermined maximum ~~batch lot number~~ or when a transmission of the additional loading request is not in time for initiating the batch-process by the batch-manufacturing apparatus, whichever occurs first.

4. (original): The method as claimed in claim 1, wherein the product comprises a semiconductor wafer, and one of the product lots comprises a plurality of the semiconductor wafer, and one of the batches comprises a plurality of the semiconductor wafer lot.

5. (original): The method as claimed in claim 4, wherein said batch-manufacturing apparatus is capable of batch-processing the plural semiconductor wafers in the single batch.

6. (currently amended): A system for managing a manufacturing processes including at least a batch-process for a batch which comprises plural product lots, and said system comprising:

a host computer;

at least a batch-manufacturing apparatus for carrying out a batch-process under control of the host computer;

at least a stoker for storing the plural product lots;

at least a carrier for carrying the plural product lots between the batch-manufacturing apparatus and the stoker under control of the host computer;

wherein a loading request is transferred from the batch-manufacturing apparatus to a host computer, and the host computer retrieves batch-processable product lots to form a batch of plural batch-processable product lots, and the batch-manufacturing apparatus verifies whether or not a [[lot]] number of the lots in the batch reaches a predetermined maximum ~~batch-lot number~~, and an additional loading request is set from the batch-manufacturing apparatus to the host computer when the predetermined maximum has not been reached, and the host computer ~~is further retrieved~~ determines whether or not any further additional batch-processable product lot is present, and the additional batch-processable product lot is carried to the batch-manufacturing apparatus to add the additional batch-processable product lot to the batch when the predetermined maximum has not

been reached and the additional batch-processable product lot is present.

7. (currently amended): The system as claimed in claim 6, wherein the additional loading request is repeatedly sent to the host computer until the lot number of the batch reaches the predetermined maximum ~~batch lot number~~.

8. (currently amended): The system as claimed in claim 6, wherein a delete request for deleting the additional loading request is sent from the batch-manufacturing apparatus to the host computer either when the [[lot]] number of the lots in the batch reaches the predetermined maximum ~~batch lot number~~ or when a transmission of the additional loading request is not in time for initiating the batch-process by the batch-manufacturing apparatus, whichever occurs first.

9. (original): The system as claimed in claim 6, wherein the system has plural blocks, each of which has at least one of the stoker and the batch-manufacturing apparatus, and at least one of the carrier is allocated to each of the plural blocks, and the host computer retrieves the wafer lots in each of the plural block and also controls each of the carriers in each of the plural blocks.

10. (original): The system as claimed in claim 6, wherein the product comprises a semiconductor wafer, and one of the product lots comprises a plurality of the semiconductor

wafer, and one of the batches comprises a plurality of the semiconductor wafer lot.

11. (original): The system as claimed in claim 10, wherein said batch-manufacturing apparatus is capable of batch-processing the plural semiconductor wafers in the single batch.